

Patent Abstracts of Japan

PUBLICATION NUMBER : 63303064
PUBLICATION DATE : 09-12-88

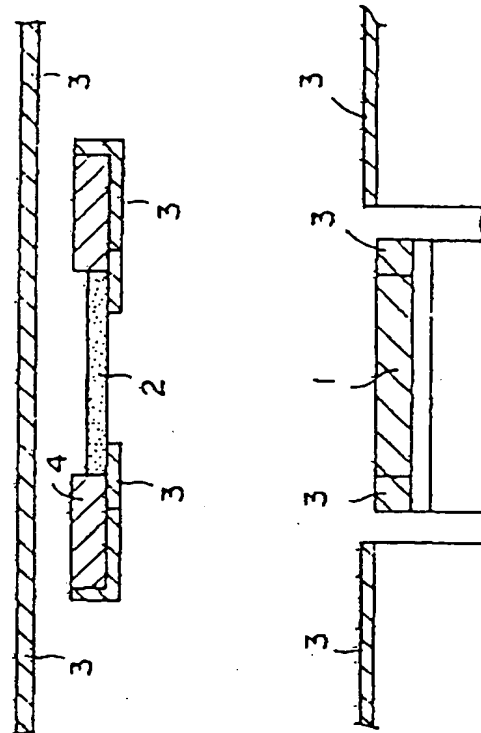
APPLICATION DATE : 30-05-87
APPLICATION NUMBER : 62133347

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INT.CL. : C23C 14/34

TITLE : SPUTTERING DEVICE



ABSTRACT : PURPOSE: To prevent the peeling of films sticking and laminated on the parts other than the body to be coated, by covering all the parts, other than the body to be coated, in a sputter chamber to which sputter grains are allowed to adhere with a material of the same substance as that of a target.

CONSTITUTION: In a sputter chamber, all the parts around a target 1 are coated with coverings 3 of the same material as that of the target 1. When the target 1 is made of hard-to-work material, the sputter chamber is prepared by using an easy-to-work material and, in this case, the inner wall of the sputter chamber may be constituted of a coated film containing a material of the same substance as that of the target 1 and adhesives. The target-side plane of a jig 4 on which a body 2 to be coated is placed is also coated with the covering 3 of the same material as that of the target. Since the adhesive strength of the sputtering film to these covering 3 is excellent, the deposit film adhering to the inner wall of the sputter chamber, the jig 4, etc., does not peel off. Accordingly, the peeling of the above film and the resulting readhesion of the film to the body to be coated can be prevented and, as a result, the necessity of the cleaning of the device can be eliminated.

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